



IFW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: **Hiroshi YOSHIDA**

Group Art Unit: **2818**

Application Number: **10/501,080**

Examiner: **Chuong A. Luu**

Filed: **December 14, 2004**

Confirmation Number: **3317**

For: **METHOD FOR GETTERING TRANSITION METAL
IMPURITIES IN SILICON CRYSTAL**

Attorney Docket Number: **042440**

Customer Number: **38834**

RESPONSE

Commissioner for Patents
P. O. Box 1450
Alexandria, VA 22313-1450

June 22, 2006

Sir:

This paper is filed in response to the Office Action dated March 27, 2006.

Amendments to the Claims begin on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.